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[10191/1466]

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s) : Volker BECKER et al.
Serial No. : To Be Assigned
Filed : Herewith
For : METHOD FOR PROCESSING SILICON BY
ETCHING PROCESSES

Examiner : To Be Assigned
Art Unit : To Be Assigned

5/A
C.t
(22/0)

Assistant Commissioner for Patents
Washington, D.C. 20231

PRELIMINARY AMENDMENT

SIR:

Kindly amend the above-identified application before examination as set forth below.

IN THE SPECIFICATION:

On page 2, after line 32, insert the heading:

--SUMMARY OF THE INVENTION-- .

On page 4, line 10, insert the heading:

--DETAILED DESCRIPTION OF THE INVENTION-- .

On page 5, line 12, change "Drawing" to --BRIEF DESCRIPTION OF THE DRAWINGS--.

IN THE CLAIMS:

On page 22, delete the first line "Patent Claims" and insert:

--WHAT IS CLAIMED IS--.